

# Mahanth Prasad

## List of Publications by Year in descending order

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Version: 2024-02-01

25  
papers

369  
citations

840776

11  
h-index

794594

19  
g-index

25  
all docs

25  
docs citations

25  
times ranked

295  
citing authors

#	ARTICLE	IF	CITATIONS
1	Development of MEMS Acoustic Sensor With Microtunnel for High SPL Measurement. IEEE Transactions on Industrial Electronics, 2022, 69, 3142-3150.	7.9	13
2	Fabrication of microchannel and diaphragm for a MEMS acoustic sensor using wet etching technique. Microelectronic Engineering, 2022, 253, 111670.	2.4	3
3	Deposition and optimization of piezoelectric zinc oxide-layer using sol-gel technique for MEMS acoustic sensor. Materials Today: Proceedings, 2021, 46, 5730-5736.	1.8	3
4	Influence of Temperature on Graphene/ZnO Heterojunction Schottky Diode Characteristics. Journal of Nanoscience and Nanotechnology, 2021, 21, 3165-3170.	0.9	2
5	Study of the effects of annealing temperature on the properties of piezoelectric ZnO thin film for the development of MEMS acoustic sensor. Materials Today: Proceedings, 2021, 46, 5737-5741.	1.8	2
6	Piezoelectric Based MEMS Acoustic Sensor for Wide Frequency Applications. IEEE Sensors Journal, 2021, 21, 27352-27360.	4.7	12
7	Piezoelectric MEMS based acoustic sensors: A review. Sensors and Actuators A: Physical, 2020, 301, 111756.	4.1	90
8	Development of Diaphragm and Microtunnel Structures for MEMS Piezoelectric Sensors. IEEE Transactions on Semiconductor Manufacturing, 2020, 33, 606-613.	1.7	10
9	Design, fabrication and reliability study of piezoelectric ZnO based structure for development of MEMS acoustic sensor. Microsystem Technologies, 2019, 25, 4517-4528.	2.0	20
10	Fabrication and Annealing Temperature Optimization for a Piezoelectric ZnO Based MEMS Acoustic Sensor. Journal of Electronic Materials, 2019, 48, 5693-5701.	2.2	15
11	High-energy 120ÅMeV Au <sup>9+</sup> ion beam-induced modifications and evaluation of craters in surface morphology of SnO <sub>2</sub> and TiO <sub>2</sub> nanocomposite thin films. Applied Nanoscience (Switzerland), 2019, 9, 1265-1280.	3.1	15
12	Fabrication and Simulation of Piezoelectric Aluminium Nitride Based Micro Electro Mechanical System Acoustic Sensor. Journal of Nanoelectronics and Optoelectronics, 2019, 14, 1267-1274.	0.5	9
13	Development of micro-hotplate and its reliability for gas sensing applications. Applied Physics A: Materials Science and Processing, 2018, 124, 1.	2.3	23
14	Deposition and process development of AlN for MEMS acoustic sensor. Vacuum, 2018, 157, 349-353.	3.5	12
15	Development of Film Bulk Acoustic Wave Resonator: A Review. Sensor Letters, 2016, 14, 346-361.	0.4	7
16	Influence of Temperature on the Sensitivity of ZnO-Based MEMS Acoustic Sensor. Sensor Letters, 2016, 14, 122-126.	0.4	0
17	Design and fabrication of microtunnel and Si-diaphragm for ZnO based MEMS acoustic sensor for high SPL and low frequency application. Microsystem Technologies, 2015, 21, 1249-1255.	2.0	16
18	Design, development and reliability testing of a low power bridge-type micromachined hotplate. Microelectronics Reliability, 2015, 55, 937-944.	1.7	15

#	ARTICLE	IF	CITATIONS
19	A low-power, micromachined, double spiral hotplate for MEMS gas sensors. <i>Microsystem Technologies</i> , 2015, 21, 2123-2131.	2.0	11
20	Long-Term Effects of Relative Humidity on the Performance of ZnO-Based MEMS Acoustic Sensors. <i>IEEE Transactions on Device and Materials Reliability</i> , 2014, 14, 778-780.	2.0	3
21	ZnO Etching and Microtunnel Fabrication for High-Reliability MEMS Acoustic Sensor. <i>IEEE Transactions on Device and Materials Reliability</i> , 2014, 14, 545-554.	2.0	20
22	Design and Fabrication of Si-Diaphragm, ZnO Piezoelectric Film-Based MEMS Acoustic Sensor Using SOI Wafers. <i>IEEE Transactions on Semiconductor Manufacturing</i> , 2013, 26, 233-241.	1.7	52
23	FEM simulation of platinum-based microhotplate using different dielectric membranes for gas sensing applications. <i>Sensor Review</i> , 2012, 32, 59-65.	1.8	5
24	Controlled Chemical Etching of ZnO Film for Step Coverage in MEMS Acoustic Sensor. <i>Journal of Microelectromechanical Systems</i> , 2012, 21, 517-519.	2.5	7
25	Design and Fabrication of Piezoelectric MEMS Sensor for Acoustic Measurements. <i>Silicon</i> , 0, , 1.	3.3	4